

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants : Sakae KOYATA et al. Group Art Unit : 1792
Appl. No. : 10/561,821 Examiner : OLSEN, Allan W.
Filed : February 7, 2007 Confirmation No. : 2851
For : PROCESSING METHOD OF SILICON WAFER

CORRECTED CLAIM OF PRIORITY

Commissioner for Patents
U.S. Patent and Trademark Office
Customer Service Window, Mail Stop **AMENDMENT**
Randolph Building
401 Dulany Street
Alexandria, VA 22314

Sir:

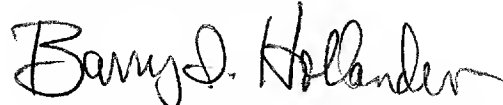
Further to the Claim of Priority filed with International Application No. PCT/JP04/15999 of which the present application is the U.S. national stage and incorrectly included in the executed Declaration filed February 7, 2007, Applicants hereby claim the right of priority granted pursuant to 35 U.S.C. 119 and 365 based upon Japanese Application No. 2003-411287, filed December 10, 2003, which priority is correctly indicated on the Official Filing Receipt. As required by 37 C.F.R. 1.55, a certified copy of the Japanese application has been received in this national stage application from the International Bureau.

Moreover, Applicants are submitting on even date herewith a Supplemental Declaration including the corrected priority information.

Authorization is hereby provided to charge any required fee for entry and/or consideration of this paper to Deposit Account No. 19-0089.

Should there be any questions, the undersigned can be reached at the below identified telephone number.

Respectfully Submitted,
Sakae KOYATA et al.


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September 30, 2009
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